



Advanced Microelectromechanical Systems

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Message from the Guest Editors

In this Special Issue, we aim to achieve innovation and the advanced development of MEMS technology in the above fields. Original research articles and reviews are welcome. Research areas may include (but are not limited to) the following:

- MEMS sensors, which are the most common application of MEMS technology with Inertial Measurement Units (IMUs), including accelerometers, gyroscopes and magnetometers, temperature sensors, flow sensors, pressure sensors, gas sensors and LIDAR.
- Artificial intelligence applications for MEMS
- MEMSs in audio, which are usually related to microphones and speakers for sound equipment.
- MEMS oscillators, which are capable of producing reference frequencies that exhibit a high degree of stability. These frequencies are utilized in many applications such as sequencing electronic systems, facilitating data transfers, establishing radio frequencies, and accurately measuring the elapsed time.
- MEMS switches, which operate at the large range of frequency from 0 Hz to more than 10 GHz, with a small leakage current in the off state and a fast response time.
- MOEMSs (micro-optoelectromechanical systems) for optical devices.





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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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